PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the Matter of the Application of: Easter, et al.
Serial No.: Unknown
Filed: October 10, 2003
For: **Retaining Ring For Use On A Carrier Of A Polishing Apparatus**
Examiner: Unknown Group Art Unit: Unknown

I hereby certify that the attached correspondence identified below is being deposited with the United States Postal Service as "Express Mail Post Office to Addressee" under 37 CFR 1.10 on the date indicated above and is addressed to:

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INFORMATION DISCLOSURE
STATEMENT TRANSMITTAL LETTER

Sir:

An Information Disclosure Statement is submitted herewith pursuant to 37 CFR §§1.97-1.98. The enclosed statement is being filed within three months of the filing date of a national application, or within three months of the date of entry into the national stage as set forth in 37 CFR §1.491 in an international application, or before the mailing date of a first Office Action on the merits, whichever event occurs last.

Respectfully submitted,

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FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	Complete if Known	
		Application Number	Unknown
		Filing Date	October 10, 2003
	INFORMATION DISCLOSURE STATEMENT BY APPLICANT	**First Named Inventor**	Easter, et al.
		Group Art Unit	Unknown
		Examiner Name	Unknown
Sheet 1 of 1		Attorney Docket Number	27757-901

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Examiner Initials		Document Number	Date	Name	Class	Sub-Class	Filing Date
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	AZ	Steigerwald, et al., "Chemical Mechanical Planarization-An Introduction," *Chemical Mechanical Planarization of Microelectronic Materials Textbook*, pages 1-81 (1997).
	BA	Nishi, et al., "Chemical-Mechanical Polish," *Handbook of Semiconductor Manufacturing Technology*, pages 419-432 (2000).

Examiner Signature		Date Considered	

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.